

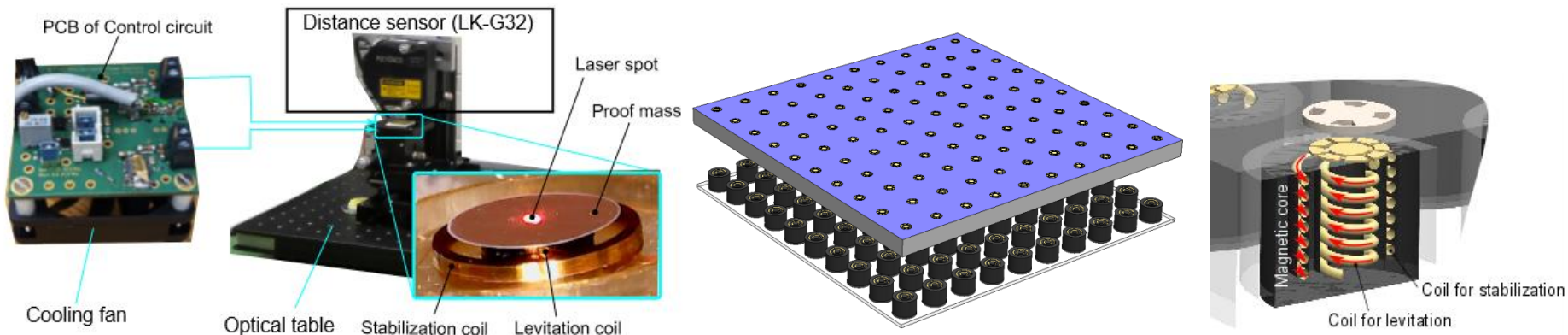
Development of Control Circuit for Inductive Levitation Micro-Actuators

Vitor Vlnieska¹, Achim Voigt¹, Sagar Wadhwa¹, Jan Korvink¹, Manfred Kohl¹, and Kirill Poletkin^{1,2}

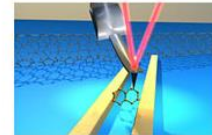
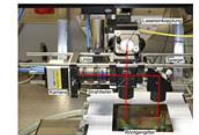
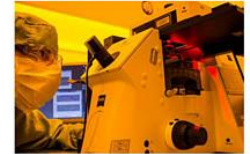
1 - Institute of Microstructure Technology - Karlsruhe Institute of Technology, Hermann-von-Helmholtz-Platz 1,76344 Eggenstein-Leopoldshafen, Germany

2 - Institute of Robotics and Computer Vision, Innopolis University, 1 Universitetskaya street, Innopolis City,420500, Russian Federation

Institute of Microstructure Technology (IMT)



- Materials Information
- Discovery Teratronics and Photonic
- Smart Nano and Microsystems
- Nanophotonics for Energy





KOMMMA

A DFG PRIORITY PROGRAMME

Cooperative Multistage Multistable Microactuator Systems



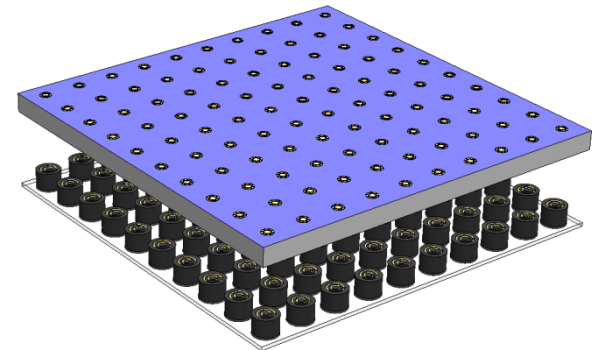
Introduction

A 2D array of cooperative hybrid levitation micro-actuators (2DAMA)

Research grant KO 1883/26-1

Investigation and development of an innovative and smart micro-actuation system.

- Newly improved performances:
 - Small operation current
 - Low operation temperature (it is comparable to the ambient temperature)
 - Considerably extended motion range
 - Wider operational capabilities
 - Transportation and manipulation of micro-objects
 - Higher accuracy and faster time of actuation
 - Significant reduction of the dissipated energy
 - Preventing a contact with harmful surfaces and the ensured long lifetimes.

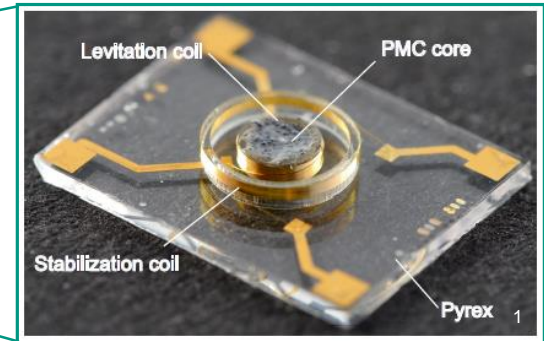


A 2D array
of micro-actuators



Introduction

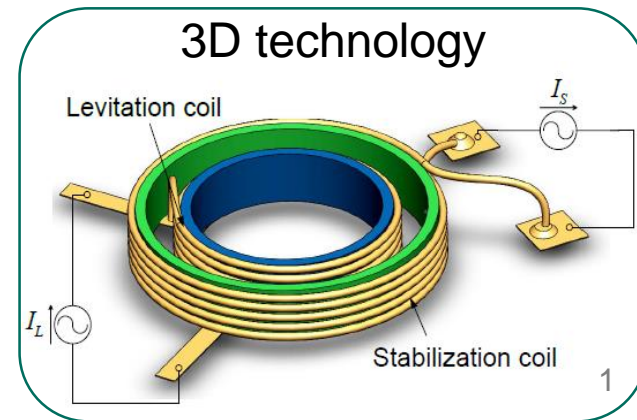
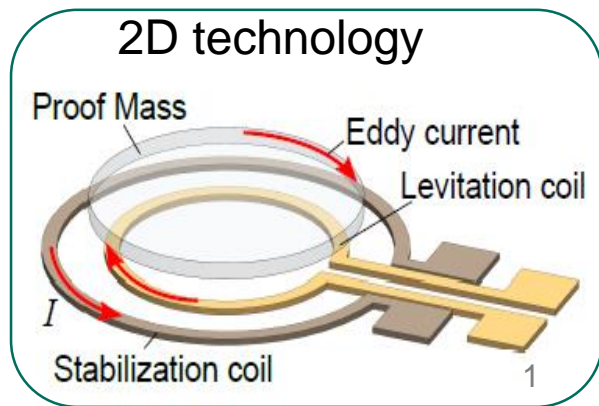
- Several techniques can provide the implementation of electromagnetic levitation into a micro-actuator systems.
- Classification according to the materials used and the sources of the force fields.
- Two major branches:
 - Electric levitation micro-actuator (ELMA)
 - Magnetic levitation micro-actuator (MLMA)
 - MLAM can be further split into:
 - Inductive (ILMA)
 - Diamagnetic (DLMA)
 - Superconducting micro-actuators
 - Hybrid levitation micro-actuators (HLMA)



1 - Poletkin, K., et al. "Energy-aware 3D micro-machined inductive suspensions with polymer magnetic composite core," Journal of Physics: Conference Series, 2018.



Methods



- Low operation temperature
- Small operation current
- Significant reduction of the dissipated energy 2

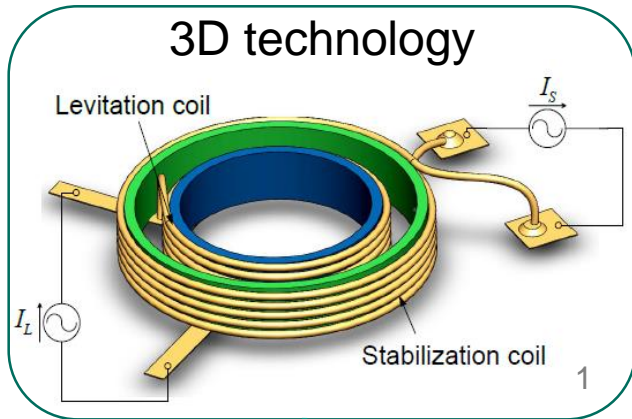
1 - Kirill Poletkin - Levitation Micro-Systems: Applications to Sensors and Actuators

2 - Lu, Z. et al. Performance Characterization of Micromachined Inductive Suspensions Based on 3D Wire-Bonded Microcoils. Micromachines, 2014.



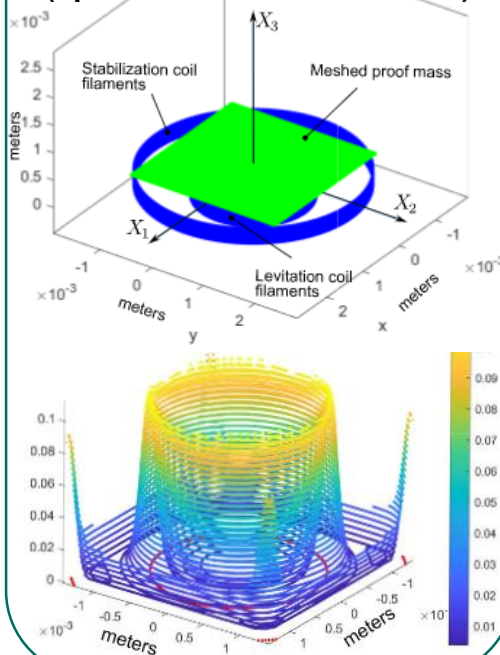
Methods

3D technology

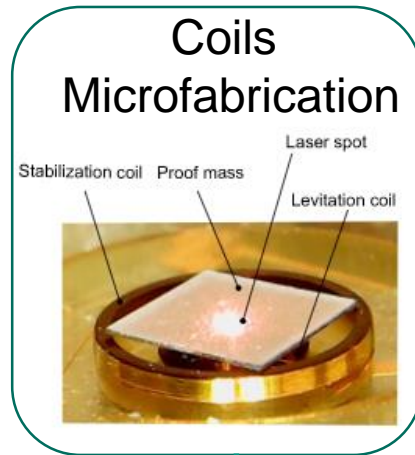


- Low operation temperature
- Small operation current
- Significant reduction of the dissipated energy

Simulation (quasi-FEM method)



Coils Microfabrication



- Current coils
- High frequency output
- Optimal design
- Coil eddy currents
- Electrical parameters

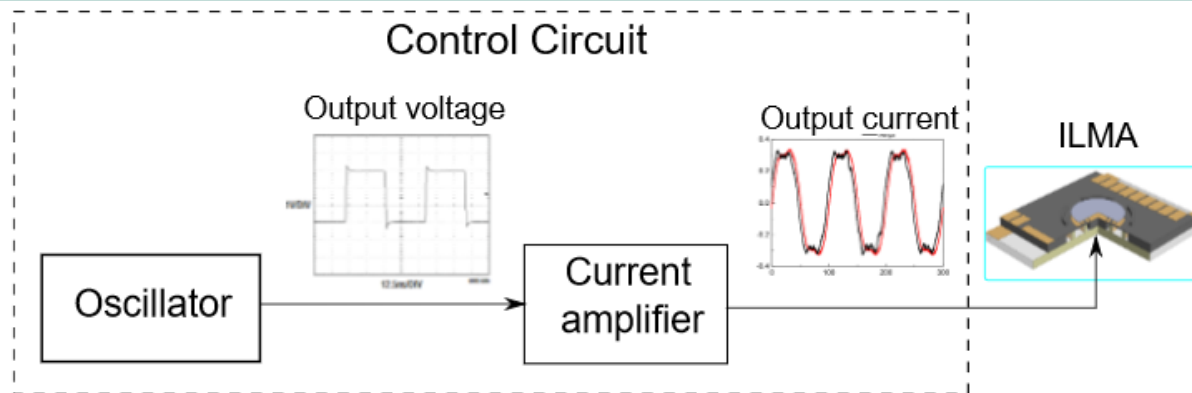
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Results

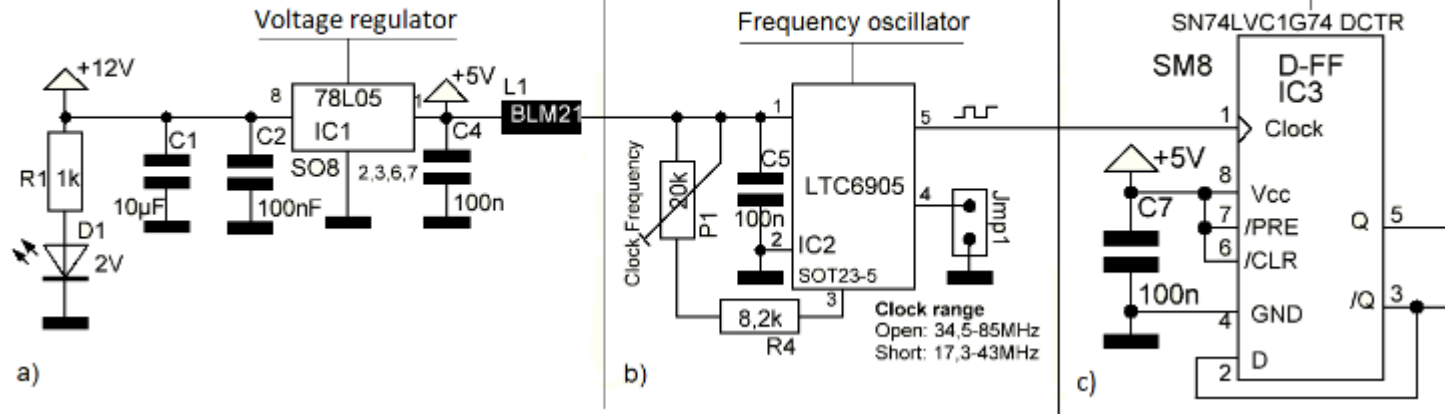
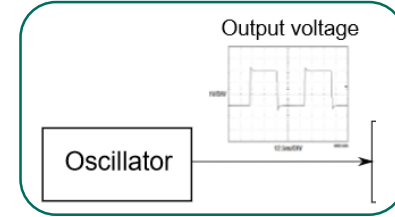
- High frequency output voltage supplier from 0 to 40 Vpp
- High frequency current (maximum peak to peak) from 0 to 400 mA
- Rectangular waveform of the current
- Frequency operation range from 8.4 to 40 MHz.

2



Development

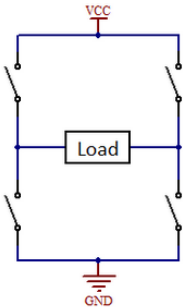
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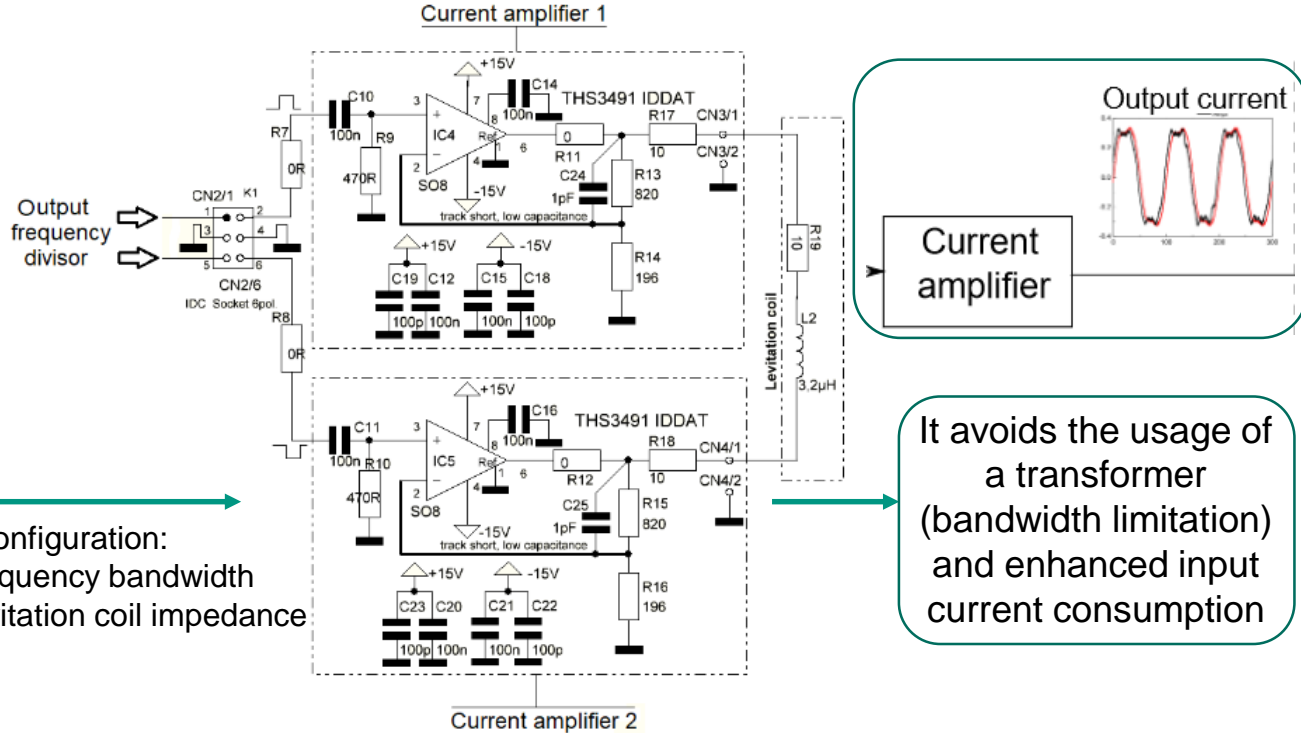
2 - Lu, Z. et al. Performance Characterization of Micromachined Inductive Suspensions Based on 3D Wire-Bonded Microcoils. *Micromachines*, 2014.

Development

- High frequency current from 0 to 400 mA 2



- H-bridge configuration:
 - High frequency bandwidth
 - High levitation coil impedance

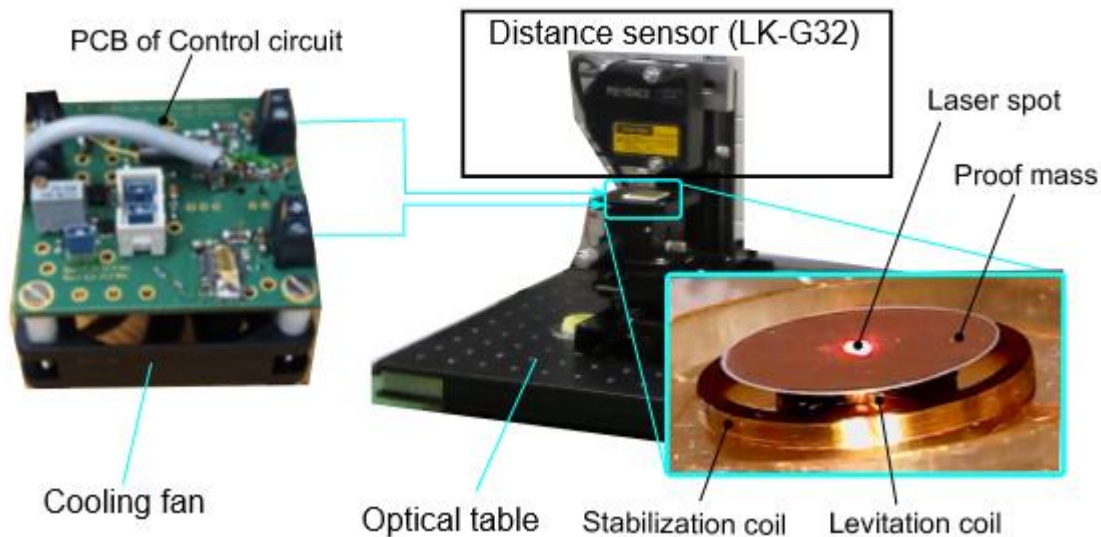


It avoids the usage of a transformer (bandwidth limitation) and enhanced input current consumption

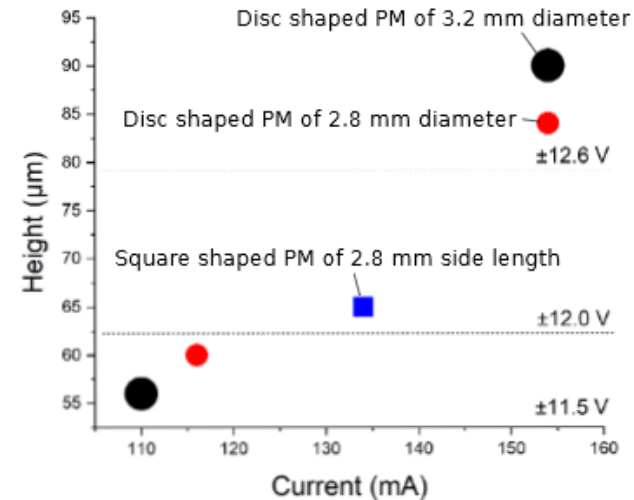
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Experimental setup



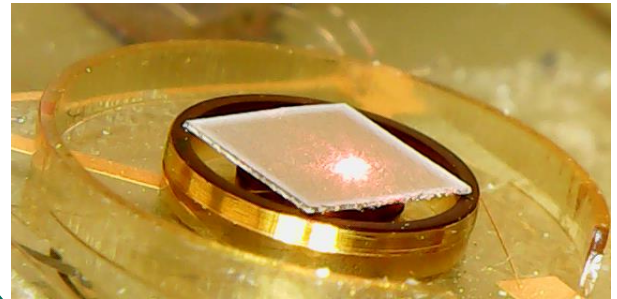
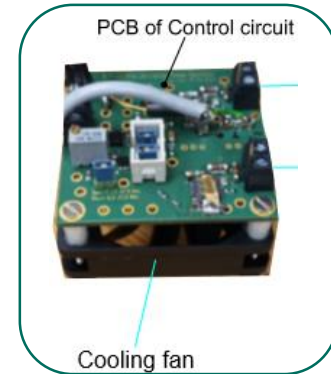
Results





Conclusions

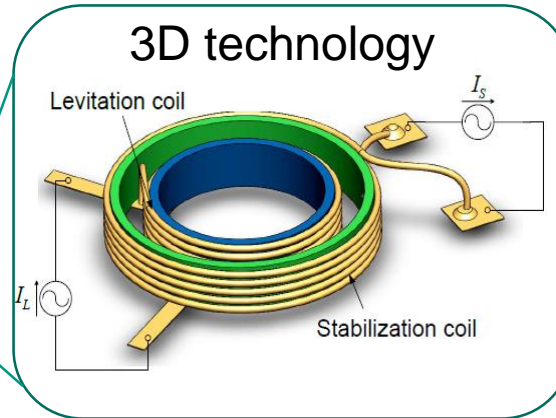
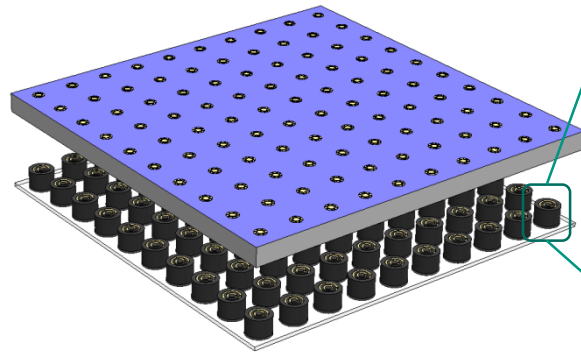
- Applying a quasi-finite element method simulation:
 - The eddy current within the square shaped PM were simulated
 - The numerical analysis of the force interaction between the coils and the levitated proof mass confirms that the two coil design is the optimum design.
- A control circuit for application to inductive levitation micro-actuators was developed
- The size dimensions (60 × 60 × 25 mm) of the control circuit were comparable with ILMA setup
- The control circuit is able to generate AC current with squared shape in a range of frequency from 8 to 43 MHz and with peak-to-peak amplitude up to 420 mA.
- Successful levitation of disc shaped PM of diameters of 2.8 and 3.2 mm and, for the first time, square shaped PM of a side length of 2.8 mm.
- This fact confirmed the efficiency of the proposed circuit design and its compatibility with micro-actuation system.





Outgoings

- Miniaturization of the control circuit
- ILMA experimental setup with an array of 3D coils



Acknowledgements

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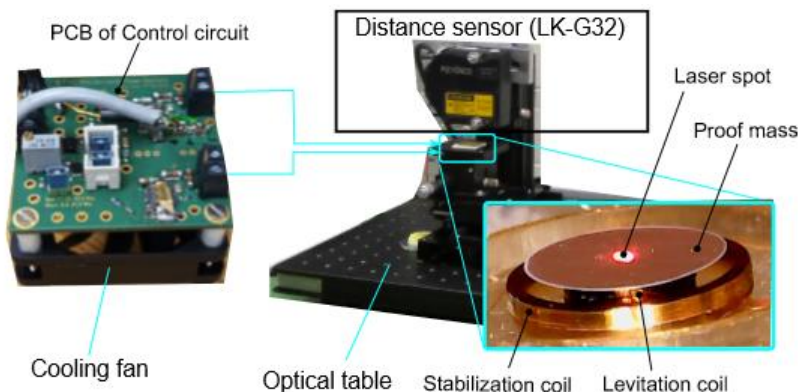
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Thank you for your attention

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